

| L Number | Hits | Search Text | DB | Time stamp |
|----------|------|---|---|------------------|
| 84 | 274 | DFB and (semiconductor near laser) and active and clad\$5 and grating and insulat\$4 and electrode | USPAT; US-PGPUB | 2003/05/02 17:08 |
| 87 | 32 | DFB and (semiconductor near laser) and active and clad\$5 and grating and (insulat\$4 with gap) and electrode | USPAT; US-PGPUB | 2003/05/02 17:09 |
| 90 | 28 | DFB and (semiconductor near laser) and active and clad\$5 and grating and (insulat\$4 with gap) and electrode | USPAT | 2003/05/02 17:36 |
| 91 | 25 | DFB and (semiconductor near laser) and active and clad\$5 and grating and (insulat\$4 with gap) and electrode and contact | USPAT | 2003/05/02 18:14 |
| 92 | 3 | DFB and (semiconductor near laser) and active and clad\$5 and (grating with InGaAs) and (insulat\$4 with gap) and electrode and contact | USPAT | 2003/05/02 18:24 |
| 93 | 8 | DFB and (semiconductor near laser) and (grating near3 InGaAs) | USPAT | 2003/05/02 18:25 |
| | 235 | (semiconductor near laser) and substrate and grating and (insulat\$ or nonconductor or non adj conductor or isolat\$) and electrode and (groove or grind or pace or rut\$ or rote) and clad\$ | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2001/10/31 14:04 |
| | 172 | ((semiconductor near laser) and substrate and grating and (insulat\$ or nonconductor or non adj conductor or isolat\$) and electrode and (groove or grind or pace or rut\$ or rote) and clad\$) and 372/\$ | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2001/11/01 09:07 |
| | 7 | ((semiconductor near laser) and (substrate near (layer or medium or film or region)) and grating and (layer near (insulat\$ or nonconductor or non adj conductor or isolat\$)) and (electrode near (layer or medium or film or region)) and (groove or grind or pace or rut\$ or rote) and (clad\$ near (layer or medium or film or region))) and 372/\$ | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2001/11/01 09:18 |
| | 86 | ((semiconductor near laser) and substrate and grating and (insulat\$ or nonconductor or non adj conductor or isolat\$) and electrode and (groove or grind or pace or rut\$ or rote) and clad\$) and 372/\$ and (waveguide near (layer or film or medium or region)) | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2001/11/01 11:31 |
| | 4 | ((semiconductor near laser) and (substrate near (layer or medium or film or region)) and grating and (layer near (insulat\$ or nonconductor or non adj conductor or isolat\$)) and (electrode near (layer or medium or film or region)) and (groove or grind or pace or rut\$ or rote) and (clad\$ near (layer or medium or film or region))) and 372/\$ and (waveguide near (layer or film or medium or region)) | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2001/11/01 09:17 |
| | 47 | ((semiconductor near laser) and substrate and grating and (insulat\$ or nonconductor or non adj conductor or isolat\$) and electrode and (groove or grind or pace or rut\$ or rote) and clad\$) and 372/\$ and (waveguide near (layer or film or medium or region)) and 372/96 | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2001/11/01 09:26 |
| | 4 | (semiconductor near laser) and (substrate near layer) and grating and (layer near (insulat\$ or nonconductor or non adj conductor or isolat\$)) and (electrode near layer) and (groove) and (clad\$ near layer) and 372/\$ and (waveguide near (layer or film or medium or region)) | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2001/11/01 09:29 |

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| | 4 | (semiconductor near laser) and (substrate near layer) and grating and (layer near (insulat\$ or nonconductor or non adj conductor or isolat\$)) and (electrode near layer) and (groove) and (clad\$ near layer) and 372/\$ and (waveguide near layer) | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2001/11/01 09:35 |
| | 40 | (({{semiconductor near laser} and substrate and grating and (insulat\$ or nonconductor or non adj conductor or isolat\$) and electrode and (groove or grind or pace or rut\$ or rote) and clad\$) and 372/\$ and (waveguide near (layer or film or medium or region))) and 372/96) and (waveguide near layer) | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2001/11/01 09:38 |
| | 8 | (semiconductor near laser) and substrate and (grating same (insulat\$ or nonconductor or non adj conductor or isolat\$) with (groove or grind or pace or rut\$ or rote)) and electrode and clad\$ and 372/\$ and (waveguide near (layer or film or medium or region)) and 372/96 and (waveguide near layer) | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2001/11/01 15:51 |
| | 6 | ((semiconductor near laser) and substrate and (grating same (insulat\$ or nonconductor or non adj conductor or isolat\$) with (groove or grind or pace or rut\$ or rote)) and electrode and clad\$ and 372/\$ and (waveguide near (layer or film or medium or region)) and 372/96 and (waveguide near layer)) and resonator | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2001/11/01 13:26 |
| | 2 | (semiconductor near laser) and substrate and (grating same (insulat\$ or nonconductor or non adj conductor or isolat\$) with (groove or grind or pace or rut\$ or rote) same resonator) and electrode and clad\$ and 372/\$ and (waveguide near (layer or film or medium or region)) and 372/96 and (waveguide near layer) | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2003/05/02 17:07 |